

Title (en)  
DETECTING DEFECTS ON A WAFER

Title (de)  
ERKENNUNG VON DEFECTEN AUF EINEM WAFER

Title (fr)  
DETECTION DES DÉFAUTS SUR UNE TRANCHE

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Application  
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Abstract (en)  
[origin: WO2010093733A2] Methods and systems for detecting defects on a wafer are provided.

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Citation (search report)  
• [I] US 2009037134 A1 20090205 - KULKARNI ASHOK [US], et al  
• [A] US 2004246476 A1 20041209 - BEVIS CHRISTOPHER F [US], et al  
• See references of WO 2010093733A2

Designated contracting state (EPC)  
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JP 5570530 B2 20140813; KR 101674698 B1 20161109; KR 20110124303 A 20111116; SG 173586 A1 20110929

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